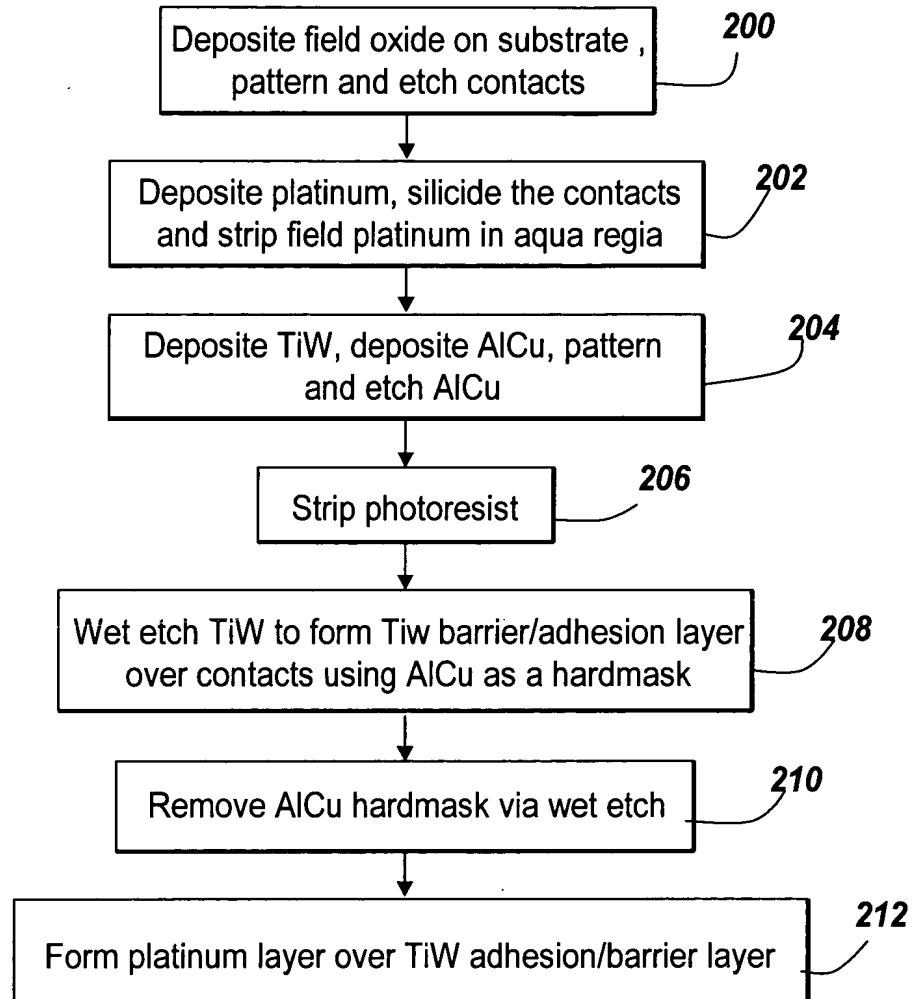


Fig. 1

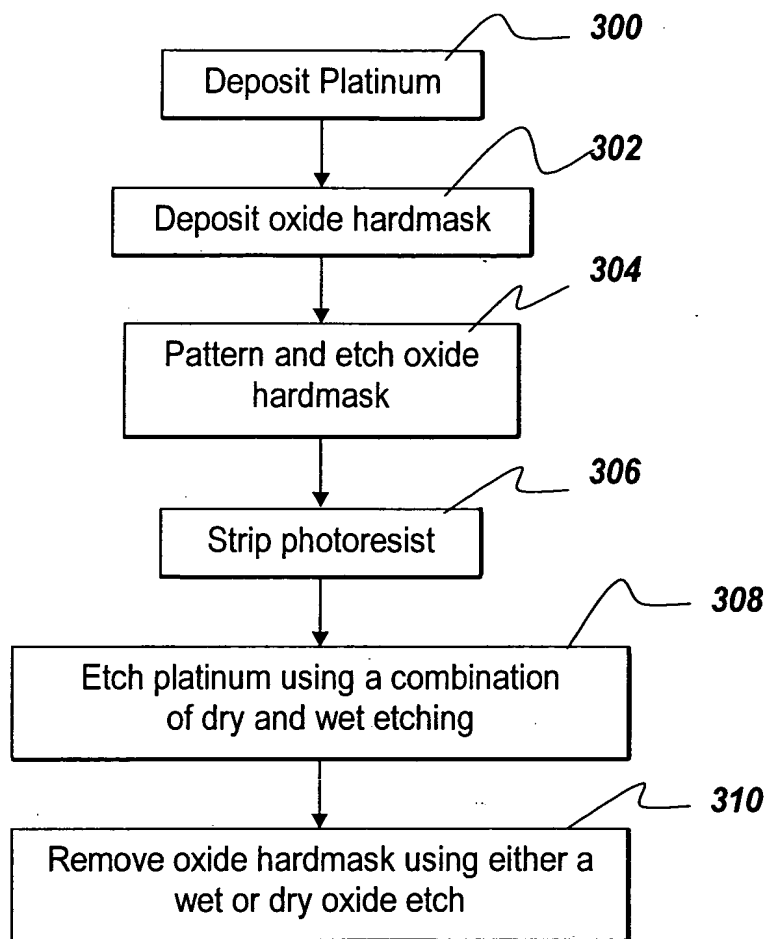


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*Fig. 2*

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*Fig. 3*

Pattern and etch contacts

Strip resist

Deposit Platinum and silicide the contacts

Strip field Pt in aqua regia

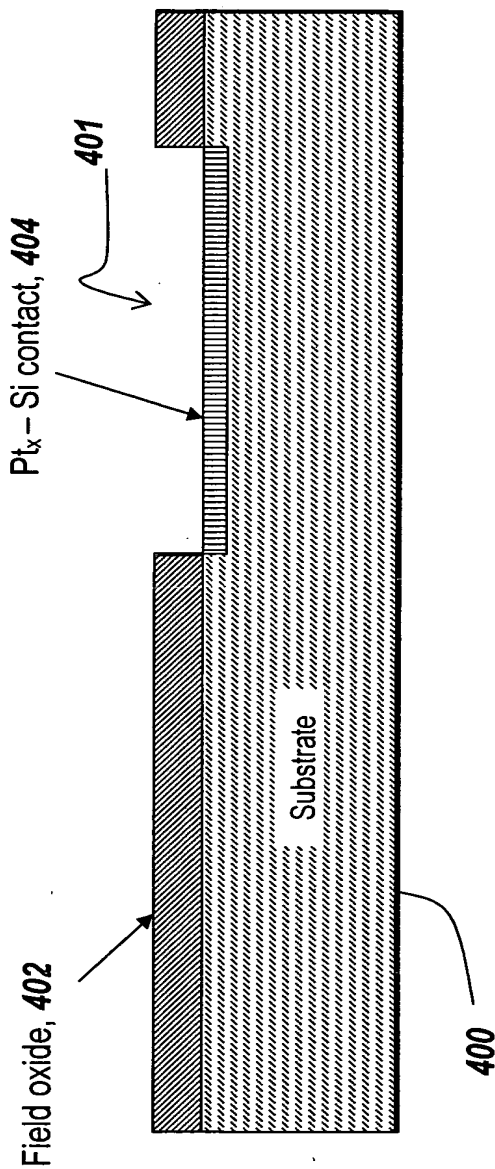


Fig. 4a



Deposit TiW  
Pattern and etch TiW barrier over contacts  
Strip resist

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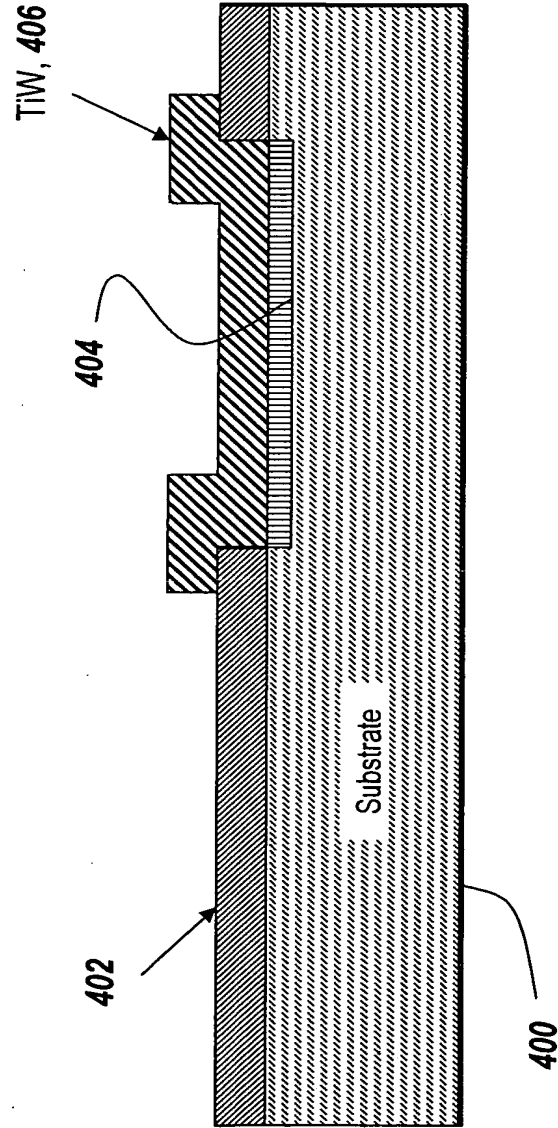


Fig. 4b

Deposit Platinum for interconnect  
Deposit oxide for hardmask  
Pattern and etch hardmask  
Strip resist

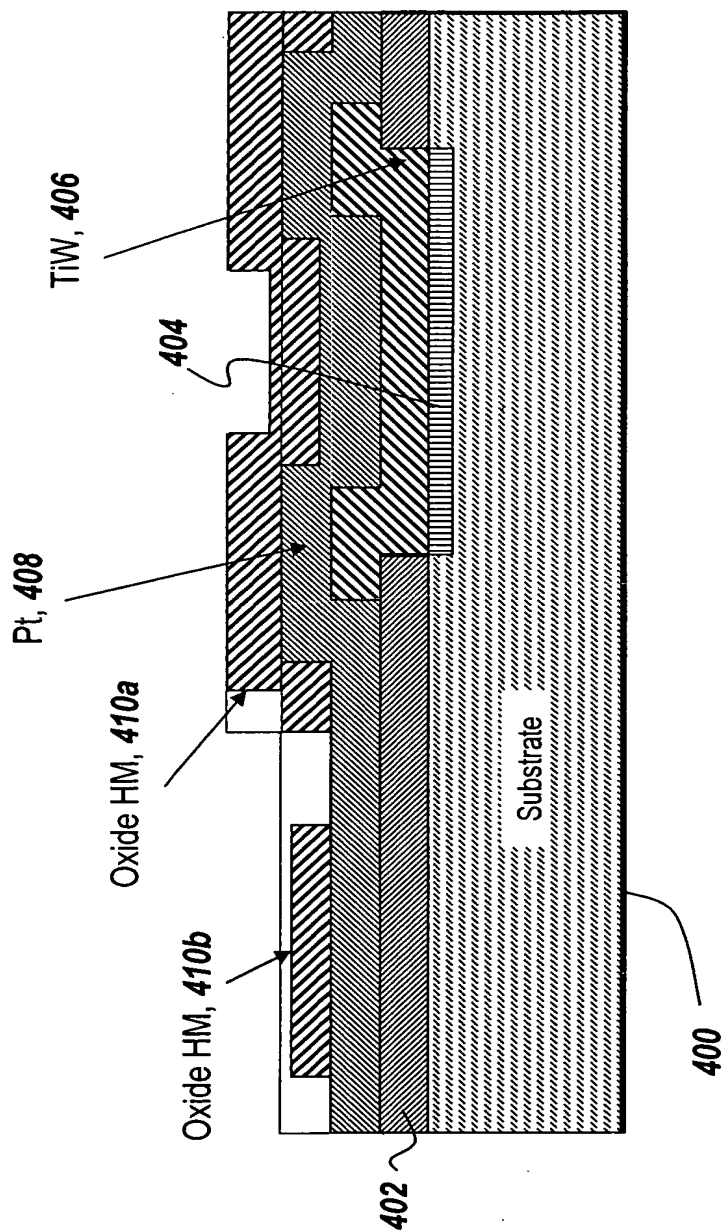


Fig. 4c

Etch Platinum for interconnect

Remove hardmask

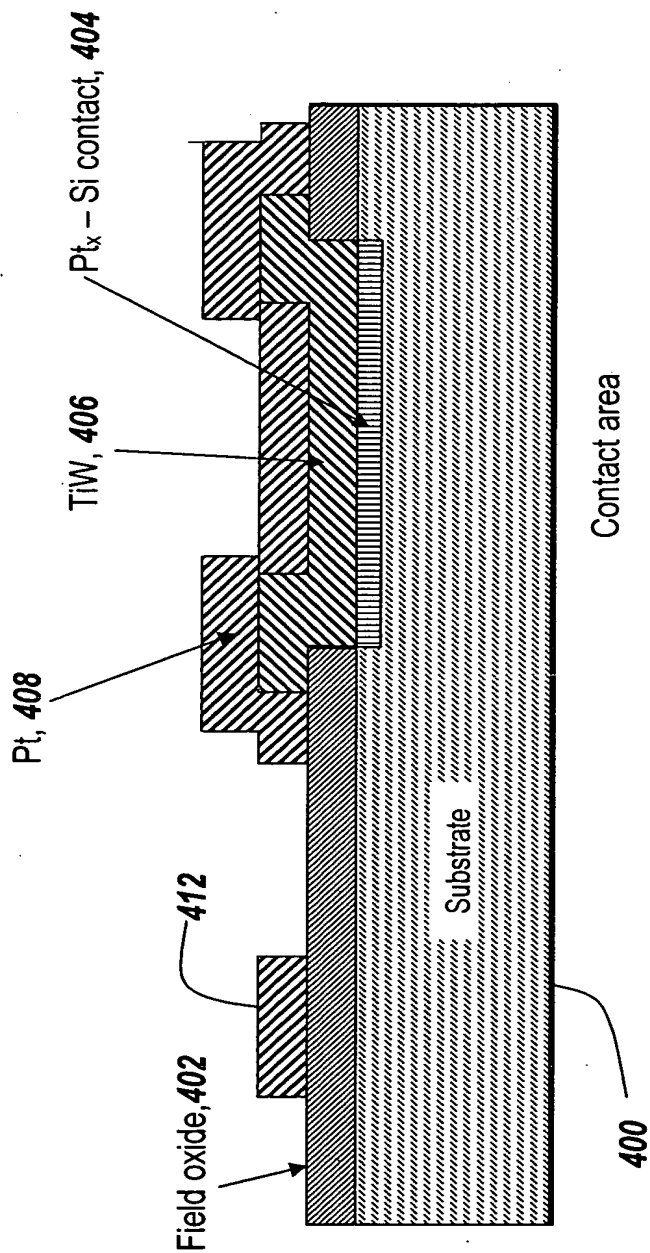
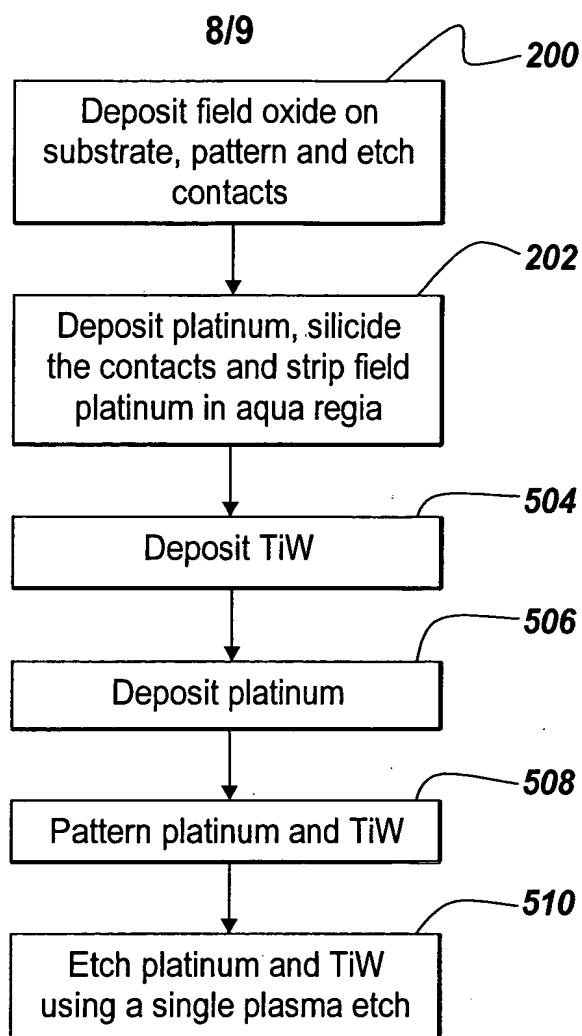


Fig. 4d



*Fig. 5*



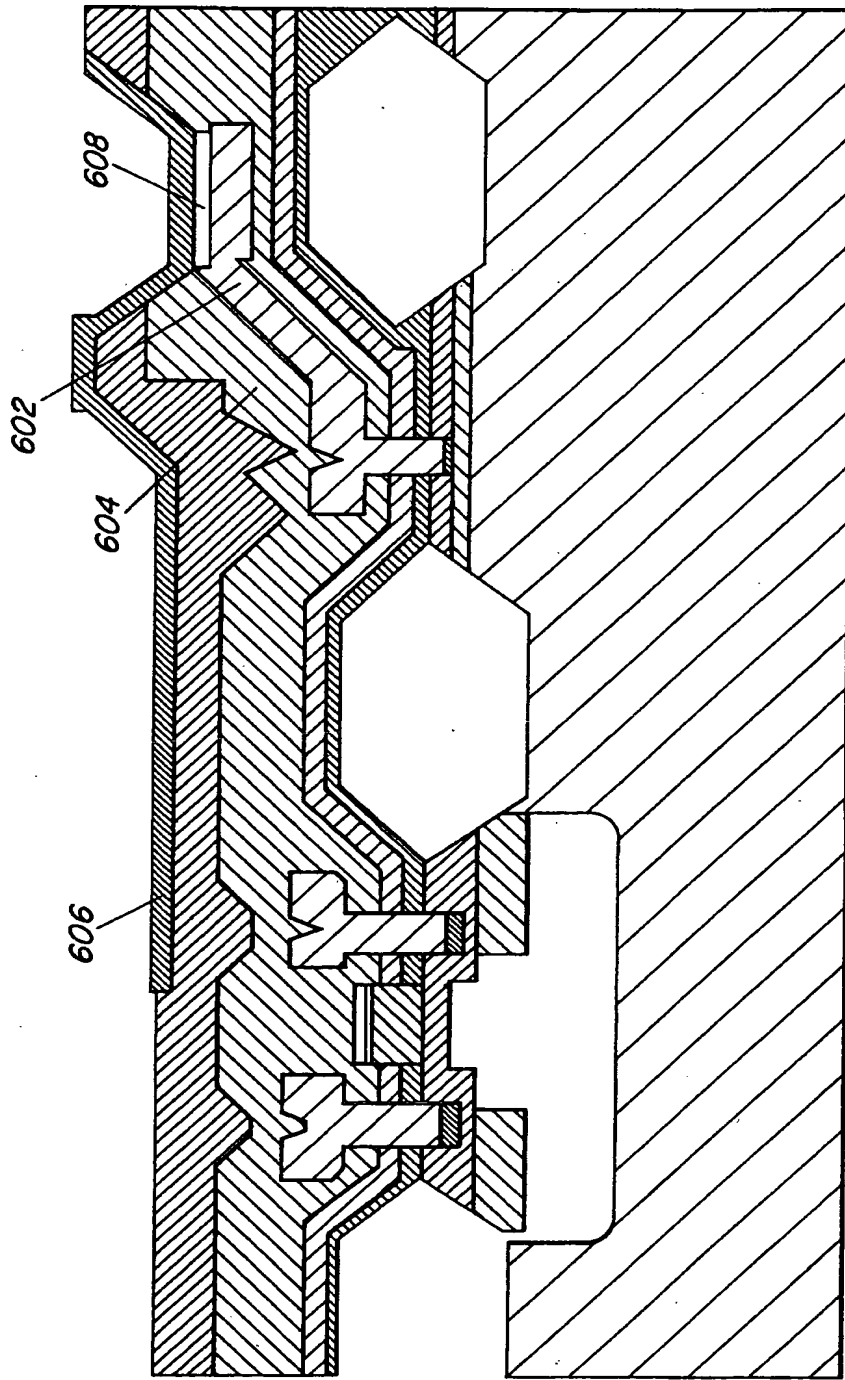


Fig. 6